App. Serial No. 10/563,483; Docket No. NL030833US1

Amendment dated: February 27, 2009

Response to Office Action dated February 5, 2009

In the Claims:

1. (Previously Presented) Semiconductor device comprising: a substrate with a

multilayer structure, the multilayer structure including a quantum well structure having a

semiconductor layer sandwiched by further layers of an electrical insulating material,

wherein the device is configured as a field effect transistor with a gate, the gate being

positioned substantially parallel to the at least one quantum well structure, and the at least

one quantum well and a further quantum well have a distance whereby the at least one

quantum well functions as a gate for the further quantum well.

2. (Previously Presented) Semiconductor device as claimed in claim 1, characterized in

that one or more multilayer substructures each comprising a further semiconductor layer

and a further electrical insulator layer are stacked on the quantum well structure forming

a superlattice.

3. (Previously presented) Semiconductor device as claimed in claim 2, characterized in

that the insulator is a high-k material having a larger dielectric constant than that of SiO<sub>2</sub>.

4. (Original) Semiconductor device as claimed in claim 3, characterized in that the high-k

material is crystalline.

5. (Previously Presented) Semiconductor device as claimed in claim 4, characterized in

that there is epitaxy between the high-k material and the semiconductor material of the

semiconductor layer.

6. (Cancelled).

7. (Cancelled).

8. (Previously Presented) Semiconductor device as claimed in claim 1, characterized in

that the insulating layer has an equivalent silicon oxide thickness of less than 1 nm.

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9. (*Previously Presented*) Semiconductor device-as claimed in claim 1, characterized in that the semiconductor layer comprises silicon.

10. (*Previously Presented*) Semiconductor device as claimed in claim 9, characterized in that the thickness of the semiconductor layer is less than 10 nm.

## 11. (Cancelled)

12. (*Previously Presented*) Semiconductor device as claimed in claim 1, characterized in that doped regions extending through the quantum well structures form electrical contacts to the quantum well structures.

13. (*Previously Presented*) Semiconductor device as claimed in claim 1, characterized in that there is opposite to the gate a further gate present, which further gate is separated from the gate by the quantum well structures.

Claims 14-22 (Cancelled)

23. (Currently Amended) The semiconductor device of claim-11, further including Semiconductor device, comprising:

a substrate with a multilayer structure, the multilayer structure including a quantum well structure having a semiconductor layer sandwiched by further layers of an electrical insulating material, wherein the semiconductor layer is enclosed by high-k materials with different dielectric constants;

another quantum well structure separated from said at least one quantum well structure, the at least one quantum well structure functioning as a gate for the other quantum well structure; and

a gate positioned substantially parallel to said at least one quantum well structure to control the semiconductor device as a field-effect transistor.